Carnegie Mellon Nanofabrication Facility rates for the 2020-2021 fiscal year are listed in the following tables. Carnegie Mellon internal users and external U.S. Federal, state, or local government organizations are charged at the "CMU" rate. External academic and 501(c)(3) charitable organizations are charged at the "Academic" rate. External corporate/industry users are charged at the "Corporate" rate.

### Nanofab Fees / Services

<table>
<thead>
<tr>
<th>Service</th>
<th>Charge Type</th>
<th>CMU</th>
<th>Academic</th>
<th>Corporate</th>
</tr>
</thead>
<tbody>
<tr>
<td>Entry Fee</td>
<td>Per Day</td>
<td>$20.60</td>
<td>$28.84</td>
<td>$41.82</td>
</tr>
<tr>
<td>Nanofab Process Development/Labor</td>
<td>Per Hour</td>
<td>$64.38</td>
<td>$90.13</td>
<td>$130.68</td>
</tr>
<tr>
<td>Wafer Dicing Service</td>
<td>Per Hour</td>
<td>$87.55</td>
<td>$122.57</td>
<td>$177.73</td>
</tr>
</tbody>
</table>

### Thin-Film Deposition Tool Rates

<table>
<thead>
<tr>
<th>Tool Name</th>
<th>Charge Type</th>
<th>CMU</th>
<th>Academic</th>
<th>Corporate</th>
</tr>
</thead>
<tbody>
<tr>
<td>Anatec Gold Coater</td>
<td>Per Run</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Angstrom Engineering Covap I Thermal Evaporator</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Cambridge Nanotech Fiji ALD System</td>
<td>Per Run + Precursor Fees</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Commonwealth Scientific Ion Beam Deposition System</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Copper Electroplating System</td>
<td>Per Run</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Nickel Electroplating System</td>
<td>Per Run</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>CVC Connexion Sputtering System</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>GVD Corporation iLab CVD</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>GVD Corporation oLab CVD</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Kurt J. Lesker PVD 75 Electron Beam Evaporator</td>
<td>Per Hour</td>
<td>$87.55</td>
<td>$122.57</td>
<td>$177.73</td>
</tr>
<tr>
<td>Kurt J. Lesker PVD 75 Sputtering System</td>
<td>Per Hour</td>
<td>$87.55</td>
<td>$122.57</td>
<td>$177.73</td>
</tr>
<tr>
<td>Leybold-Heraeus Z-400 Sputtering Systems #1 &amp; #2</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Nanofab Sputtering Systems #1 - #5</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Perkin Elmer 2400 6J Sputtering System</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Perkin Elmer 2400 8L Sputtering System</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>SCS Labcoter 2 Parylene Deposition System</td>
<td>Per Run</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Tegal AMS AlN Sputtering System</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Trion Orion II PECVD System</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Ultek E. Beam Evaporator</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
</tbody>
</table>
### ETCHING, POLISHING, & DICING TOOL RATES

<table>
<thead>
<tr>
<th>Tool Name</th>
<th>Charge Type</th>
<th>CMU</th>
<th>Academic</th>
<th>Corporate</th>
</tr>
</thead>
<tbody>
<tr>
<td>IPC Barrel Etcher</td>
<td>Per Hour</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Plasma-Therm 790 RIE System</td>
<td>Per Hour</td>
<td>$66.95</td>
<td>$93.73</td>
<td>$135.91</td>
</tr>
<tr>
<td>Plasma-Therm Versaline ICP RIE</td>
<td>Per Hour</td>
<td>$87.55</td>
<td>$122.57</td>
<td>$177.73</td>
</tr>
<tr>
<td>SPTS Primaxx Uetch Vapor HF Etcher</td>
<td>Per Hour</td>
<td>$82.40</td>
<td>$115.36</td>
<td>$167.27</td>
</tr>
<tr>
<td>Surface Technology Systems Multiplex ICP RIE &amp; Aspect Cluster ICP RIE / AOE</td>
<td>Per Hour</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Trion Phantom II RIE System</td>
<td>Per Hour</td>
<td>$66.95</td>
<td>$93.73</td>
<td>$135.91</td>
</tr>
<tr>
<td>Commonwealth Scientific Ion Beam Etching Systems #1 &amp; #2</td>
<td>Per Run</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Intlvac Nanoquest II Ion Mill</td>
<td>Per Hour</td>
<td>$87.55</td>
<td>$122.57</td>
<td>$177.73</td>
</tr>
<tr>
<td>Samco UV-1 Ozone Cleaner</td>
<td>Per Run</td>
<td>$20.60</td>
<td>$28.84</td>
<td>$41.82</td>
</tr>
<tr>
<td>Strasbaugh 6EC CMP</td>
<td>Per Hour</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Tousimis Critical Point Dryer</td>
<td>Per Run</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Xactix Xetch XeF2 Etcher</td>
<td>Per Hour</td>
<td>$30.90</td>
<td>$43.26</td>
<td>$62.73</td>
</tr>
</tbody>
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### LITHOGRAPHY TOOL RATES

<table>
<thead>
<tr>
<th>Tool Name</th>
<th>Charge Type</th>
<th>CMU</th>
<th>Academic</th>
<th>Corporate</th>
</tr>
</thead>
<tbody>
<tr>
<td>ASML 5500/80 i-Line Wafer Stepper</td>
<td>Per Hour</td>
<td>$103.00</td>
<td>$144.20</td>
<td>$209.09</td>
</tr>
<tr>
<td>Elionix ELS-G100 Electron Beam Lithography System</td>
<td>Per Hour</td>
<td>$128.75</td>
<td>$180.25</td>
<td>$261.36</td>
</tr>
<tr>
<td>FEI Sirion SEM W ith Nabity E. Beam Lithography System #1 &amp; #2</td>
<td>Per Hour</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
<tr>
<td>Heidelberg DWL 66FS</td>
<td>*Per Hour (for Litho)</td>
<td>$25.75</td>
<td>$36.05</td>
<td>$52.27</td>
</tr>
<tr>
<td></td>
<td>*Per 4&quot; Photo Mask</td>
<td>$275.00</td>
<td>$330.00</td>
<td>$410.00</td>
</tr>
<tr>
<td></td>
<td>*Per 5&quot; Photo Mask</td>
<td>$340.00</td>
<td>$415.00</td>
<td>$525.00</td>
</tr>
<tr>
<td></td>
<td>*Per 6&quot; Photo Mask</td>
<td>$500.00</td>
<td>$610.00</td>
<td>$770.00</td>
</tr>
<tr>
<td></td>
<td>*Per 7&quot; Photo Mask</td>
<td>$600.00</td>
<td>$730.00</td>
<td>$925.00</td>
</tr>
<tr>
<td>Hot Pack Vacuum Oven</td>
<td>Per Run</td>
<td>$25.75</td>
<td>$36.05</td>
<td>$52.27</td>
</tr>
<tr>
<td>Karl Suss MA56 Mask Aligner</td>
<td>Per Hour</td>
<td>$61.80</td>
<td>$86.52</td>
<td>$125.45</td>
</tr>
<tr>
<td>Karl Suss MA6 Mask Aligner</td>
<td>Per Hour</td>
<td>$72.10</td>
<td>$100.94</td>
<td>$146.36</td>
</tr>
<tr>
<td>Karl Suss MB3 Mask Aligner</td>
<td>Per Hour</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>YES HMDS Vapor Prime Oven</td>
<td>Per Run</td>
<td>$25.75</td>
<td>$36.05</td>
<td>$52.27</td>
</tr>
</tbody>
</table>

*Per mask charges are for masks produced by Nanofab staff (i.e. fee-for-service). The rate listed is a flat rate per mask, which includes labor, consumables (mask plate, resist, etchants, etc.), and machine time. They are not subject to the monthly rate cap. Masks produced by users without staff assistance will be charged at the per hour rate for lithography, and the cost of the mask plates and additional consumables will be charged separately (they must be purchased as consumable supplies in FOM).
### Furnace / Annealing Tool Rates

<table>
<thead>
<tr>
<th>Charge Type</th>
<th>CMU</th>
<th>Academic</th>
<th>Corporate</th>
</tr>
</thead>
<tbody>
<tr>
<td>AG Associates Rapid Thermal Annealer</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Annealing Furnace</td>
<td>$25.75</td>
<td>$36.05</td>
<td>$52.27</td>
</tr>
<tr>
<td>Magnetic Field Vacuum Annealer</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Oxidation Furnace</td>
<td>$154.50</td>
<td>$216.30</td>
<td>$313.64</td>
</tr>
<tr>
<td>Thermcraft 2” Barrel Furnace</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Vapor-Temp Relative Humidity Chamber</td>
<td>$25.75</td>
<td>$36.05</td>
<td>$52.27</td>
</tr>
</tbody>
</table>

### Metrology & Inspection Tool Rates

<table>
<thead>
<tr>
<th>Charge Type</th>
<th>CMU</th>
<th>Academic</th>
<th>Corporate</th>
</tr>
</thead>
<tbody>
<tr>
<td>KLA-Tencor P-2 and P-15 Profilometers</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>Nanometrics Nanospec 210XP</td>
<td>$41.20</td>
<td>$57.68</td>
<td>$83.64</td>
</tr>
<tr>
<td>Olympus MX80 Microscope With Optronics Digital Camera System</td>
<td>$25.75</td>
<td>$36.05</td>
<td>$52.27</td>
</tr>
<tr>
<td>Tencor Alpha-Step 200 Profilometer</td>
<td>$41.20</td>
<td>$57.68</td>
<td>$83.64</td>
</tr>
<tr>
<td>Tencor Flexus Stress Measurement System</td>
<td>$51.50</td>
<td>$72.10</td>
<td>$104.55</td>
</tr>
<tr>
<td>FEI Sirion SEM With Nabity E. Beam Lithography System #1 &amp; #2</td>
<td>$77.25</td>
<td>$108.15</td>
<td>$156.82</td>
</tr>
</tbody>
</table>

### Hourly Rates

Labor rates and machine time for hourly equipment is all billed based on actual time used rounded to the unit of minutes, with each machine having a minimum charge per run billed at 40% of the hourly rate. For example, the charges for using a piece of equipment having an hourly rate of $50/hr would be $20 for a 10min run or $75 for a run lasting 1hr and 30min.

### Monthly Expense Caps

The Carnegie Mellon Nanofabrication Facility has an expense cap on entry and equipment fees charged to Carnegie Mellon users, as well as 501(c)(3) and U.S. federal, state, and local government organizations (there is no cap for external corporate users). Cap fees are as follows:

- **Carnegie Mellon Users and U.S. Federal, State, and Local Government Users**
  - The entry fee cap is $260 a month per user per account number
  - The equipment fee cap is $2,575 a month per user per account number

- **501(c)(3) Users**
  - The entry fee cap is $365 a month per user per account number
  - The equipment fee cap is $3,600 a month per user per account number

These caps are the maximum amount that an individual user’s account can be charged in a single calendar month. The cap begins on the 1st of every month and goes until the last day of that month. Multiple users using the same account number or working for the same organization (in the case of external 501(c)(3), U.S. Federal, State, and Local Government Organizations) are each subject to their own cap. One user using multiple account numbers is subject to a cap for each account number. Labor fees, material fees, staff-generated photomasks, and service fees are not subject to the cap.
Precursor Fees
Atomic layer depositions are subject to an additional fee to compensate for the high cost of the precursors. Fees will vary by precursor and will be calculated based on precursor cost at time of purchase divided by the projected number of runs. Fees may range from $5.00 per 10nm to more than $100 per 10nm depending on the material. Specialty materials, such as Pt, are especially costly. Users should contact Nanofab staff regarding questions about precursor costs.

Precious Metal Fees
Precious metal thin film depositions are subject to an additional fee to compensate for the high cost of the material. These prices are subject to change based on current market values.

Sputtering runs are charged the following additional fee (pre-sputtering is added to the total deposition):

- Gold: $10.00 per every 100 Nanometers per run.
- Platinum: $13.00 per every 100 Nanometers per run.

Precious metal evaporation sources are weighed before and after evaporation to determine the amount used. The fee per run is based on the current Engelhard Fabricated Precious Metal Price plus 25% to cover reclamation and fabrication costs.